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Docket No.	Serial No.
7954/DSM/BCVD/JW	10/697,731
Applicant Yim, et al.	Confirmation No.:
Filing Date	Group
October 29, 2003	3661
	Applicant Yim, et al. Filing Date

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*Examiner Initial	Doce	Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date Appropriate	
m·m	A1	2002/0078770	06/27/2002	Hunter	73	865.9	1	
	A2	2002/0092369	07/18/2002	Hunter	73	865.9		
	A3	2002/0101508	08/01/2002	Pollack	348	85		
	A4	2003/0001083	01/02/2003	Corrado et al.	250	239		
	A5	2003/0198376	10/23/2003	Sadighi et al.	382	153		
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		Number					YES	NO
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	B2							
	В3							
	B4							

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U.S. Depart	tment	of Commerce, Patent and Trademark Office	Docket No.	Serial No.			
(PTO Form	1449	modified)	7954/DSM/BCVD/JW	10/697,731			
INFORMAT	ION	DISCLOSURE STATEMENT BY APPLICANT	Applicant Yim, et al.	Confirmation No.:			
(Use severa	al she	ets if necessary)	Filing Date	Group			
		Examiner M. Marchall 15 Was	October 29, 2003	3661			
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OTHER ART							
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.					
m•m	C1	"Wafercam <sup>tm</sup> System: Wireless Camera System for Semiconductor Processing Robotic Arm Calibration", <a href="https://www.gtweed.com/semiconductor/Wafercam.htm">www.gtweed.com/semiconductor/Wafercam.htm</a> , printed 12/10/2002					
	C2						
	СЗ						
Examiner McDieunel Marc Date Considered 10-06-05							
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							